



**PATENT**  
Attorney Docket No.: SSI-00501

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

Maximilian A. Biberger et al.

Serial No.: 09/912,844

Filed: July 24, 2001

For: **HIGH PRESSURE PROCESSING  
CHAMBER FOR  
SEMICONDUCTOR SUBSTRATE**

Assistant Commissioner for Patents  
Washington, D.C. 20231

} Group Art Unit: 1763  
} Examiner: Ram N. Kackar  
} **AMENDMENT AND RESPONSE TO  
OFFICE ACTION MAILED ON  
November 13, 2002**  
} 162 North Wolfe Road  
} Sunnyvale, California 94086  
} (408) 530-9700

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FEB 25 2003  
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HIA  
2/26/03  
MW

Sir:

These amendment and remarks are submitted in response to the Office Action mailed on November 13, 2002.

**AMENDMENT**

Clean version of the amended claims:

*A /*  
*Sub B1*  
(Once Amended) 16. The apparatus of claim 15 wherein the high pressure processing chamber is a supercritical processing chamber.

(Once Amended) 17. The apparatus of claim 15 where the high pressure processing chamber is a non-supercritical processing chamber.

**CERTIFICATE OF MAILING (37 CFR § 1.8(a))**

I hereby certify that this paper (along with any referred to as being attached or enclosed) is being deposited with the U.S. Postal Service on the date shown below with sufficient postage as first class mail in an envelope addressed to the: Assistant Commissioner for Patents, Washington D.C. 20231

HAVERSTOCK & OWENS LLP.

Date: 2/13/03

*J. H. C.*